

IPBPM piezo-mover system and plans for in situ monitoring of calibration and stability

Current status and plan for ATF2

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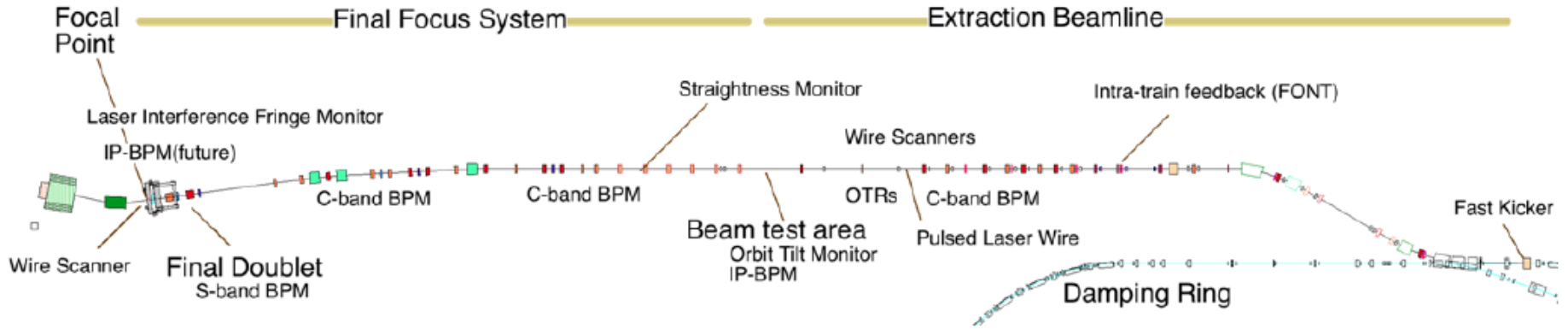
On behalf of and collaborating with:

Oscar Blanco (LAL, CERN), Frédéric Bogard, Patrick Cornebise, Jean-Philippe Dugal, Si-Won-Jang (KNU), Toshiaki Tauchi (KEK), Nobuhiro Terunuma (KEK), Sandry Wallon

Motivation

- ▶ Small vertical beam size (goal 1)
 - ▶ Achieve $\sim 37\text{nm}$
 - ▶ Validate Local chromaticity correction
- ▶ Stabilization of beam center (goal 2)
 - ▶ down to $\sim 2\text{nm}$

Methodology for stabilization



Goal 1 (beam size ~ 37 nm)

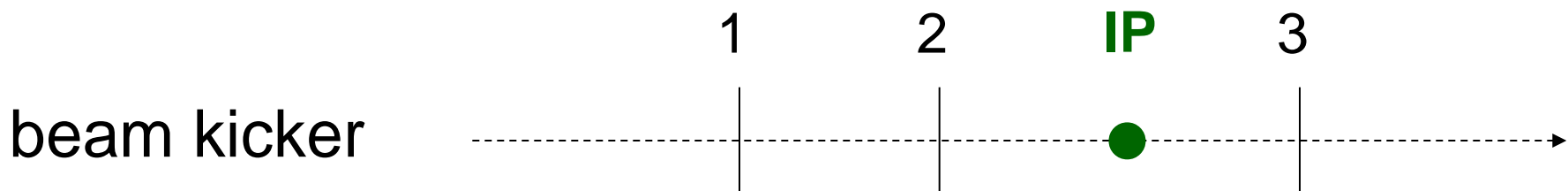
Goal 2 (nm-scale stability with feedback)

beam jitter < 10 nm

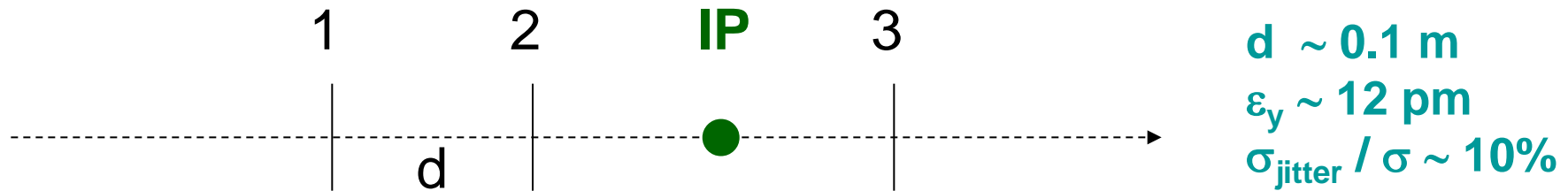
beam jitter ~ 2 nm

1. Measure stability at one of IP-BPMs after shifting the beam waists there
2. Infer position from measurements at the two other IP-BPMs
3. Use fast kicker just upstream to correct second bunch within ATF2 train
4. Optional: use fast feedback upstream to check for improved IP stability
5. Optional: use fast kicker upstream for corrections based on IP-BPMs
6. Optional (goal 1): correct data if second bunch in IP-BSM beam size analysis

in all cases \rightarrow must first calibrate **scale factors** and study **system resolution**



Required precision on relative IP-BPM **scale factors** depends on beam parameters



$$\theta_{\text{IP}} = (y_2 - y_1) / d$$

$$y_{\text{IP}} = 2 y_2 - y_1$$

ξ = calibration error of 1 relative to 2

$$\rightarrow 2 y_2 - y_1 \sim y_{\text{IP}} + 2 \xi \theta d$$

1. Determination of resolution
2. Feedback to IP or to 3rd IP-BPM

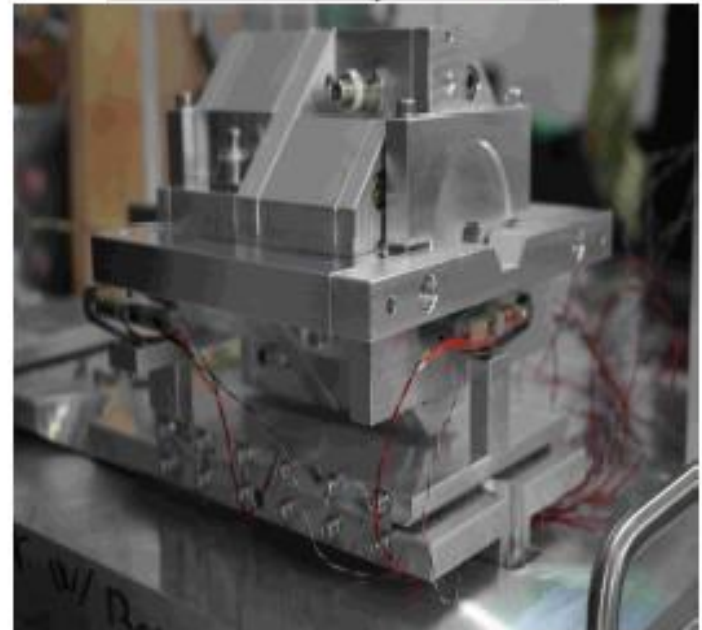
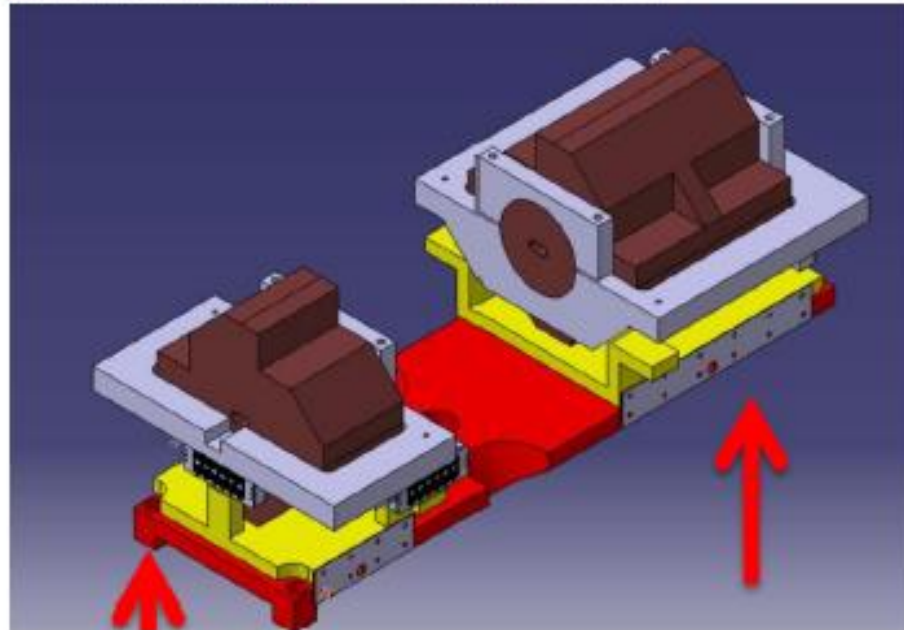
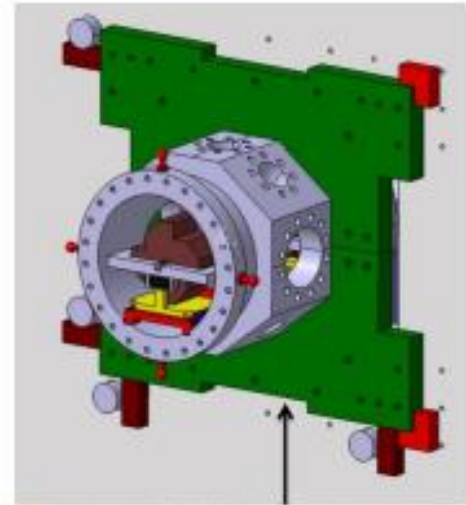
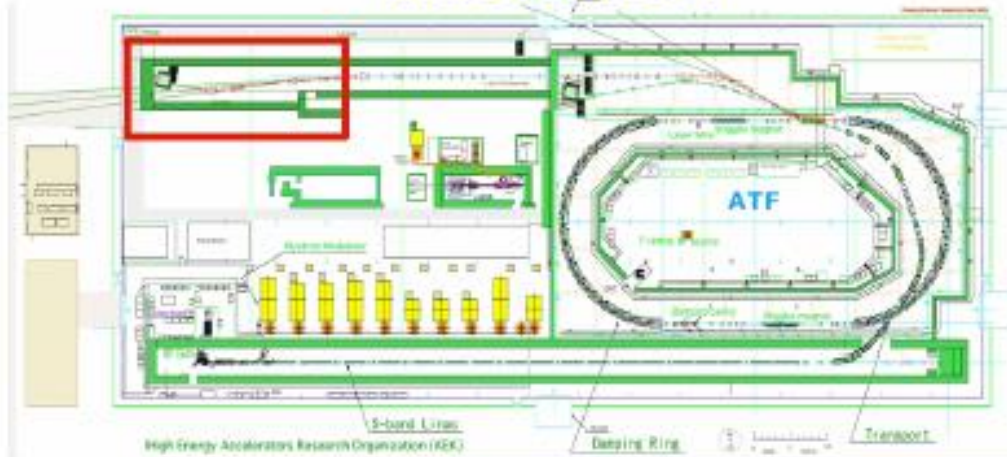
$\beta \sim 1 \text{ m}$ (e.g. diagnostic section)

$$\text{Residual} \sim 2 (\epsilon / \beta)^{0.5} d (\sigma_{\text{jitter}} / \sigma) \xi \sim 10^{-7} \xi \rightarrow \xi \sim 10^{-2} \text{ for } 1 \text{ nm error}$$

$\beta \sim 10^{-4} \text{ m}$ (interaction point : nominal optics)

$$\text{Residual} \sim 2 (\epsilon / \beta)^{0.5} d (\sigma_{\text{jitter}} / \sigma) \xi \sim 10^{-5} \xi \rightarrow \xi \sim 10^{-4/-3} \text{ for } 1 / 10 \text{ nm error}$$

ATF2 LAYOUT

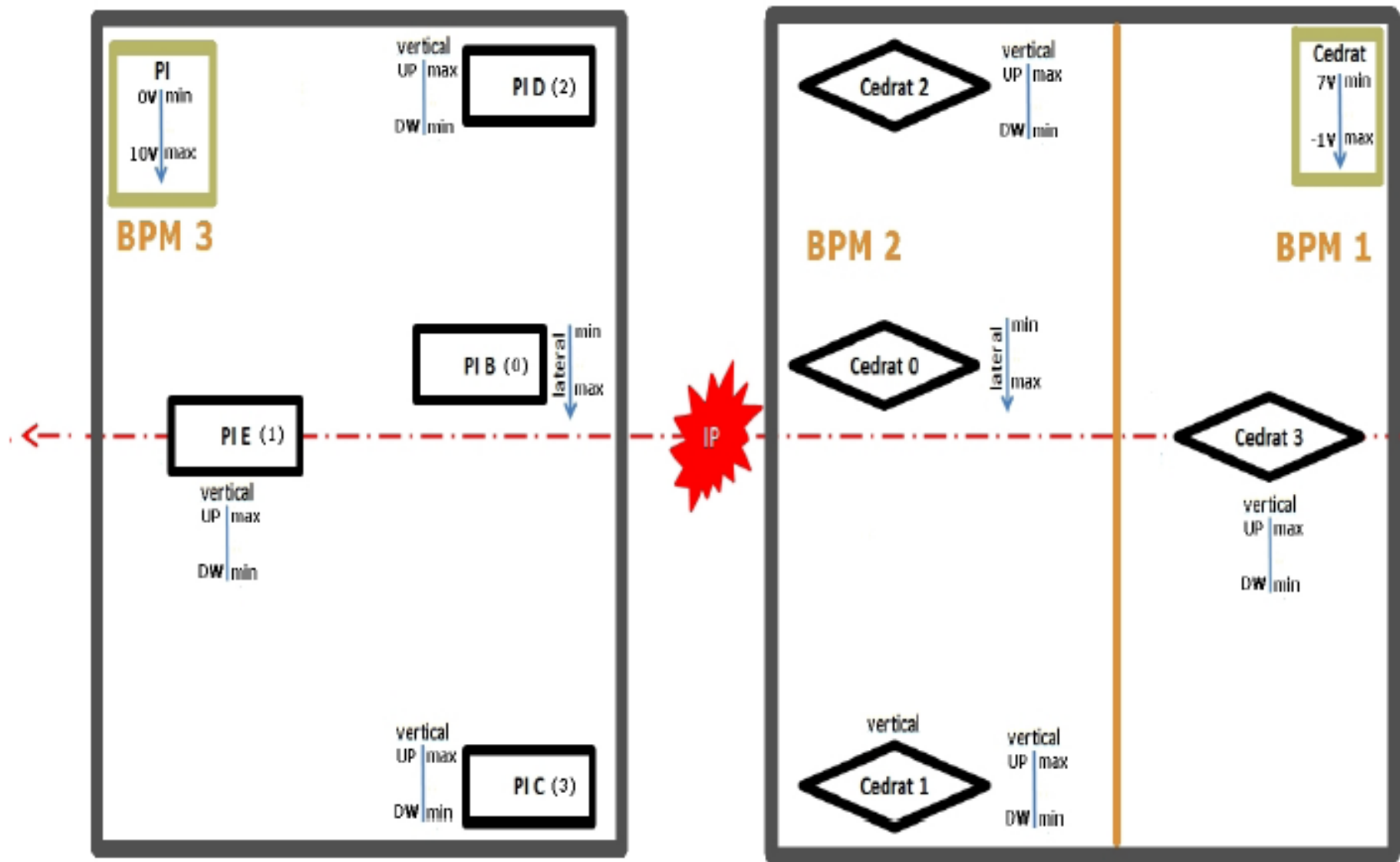


Motivation (cont.)

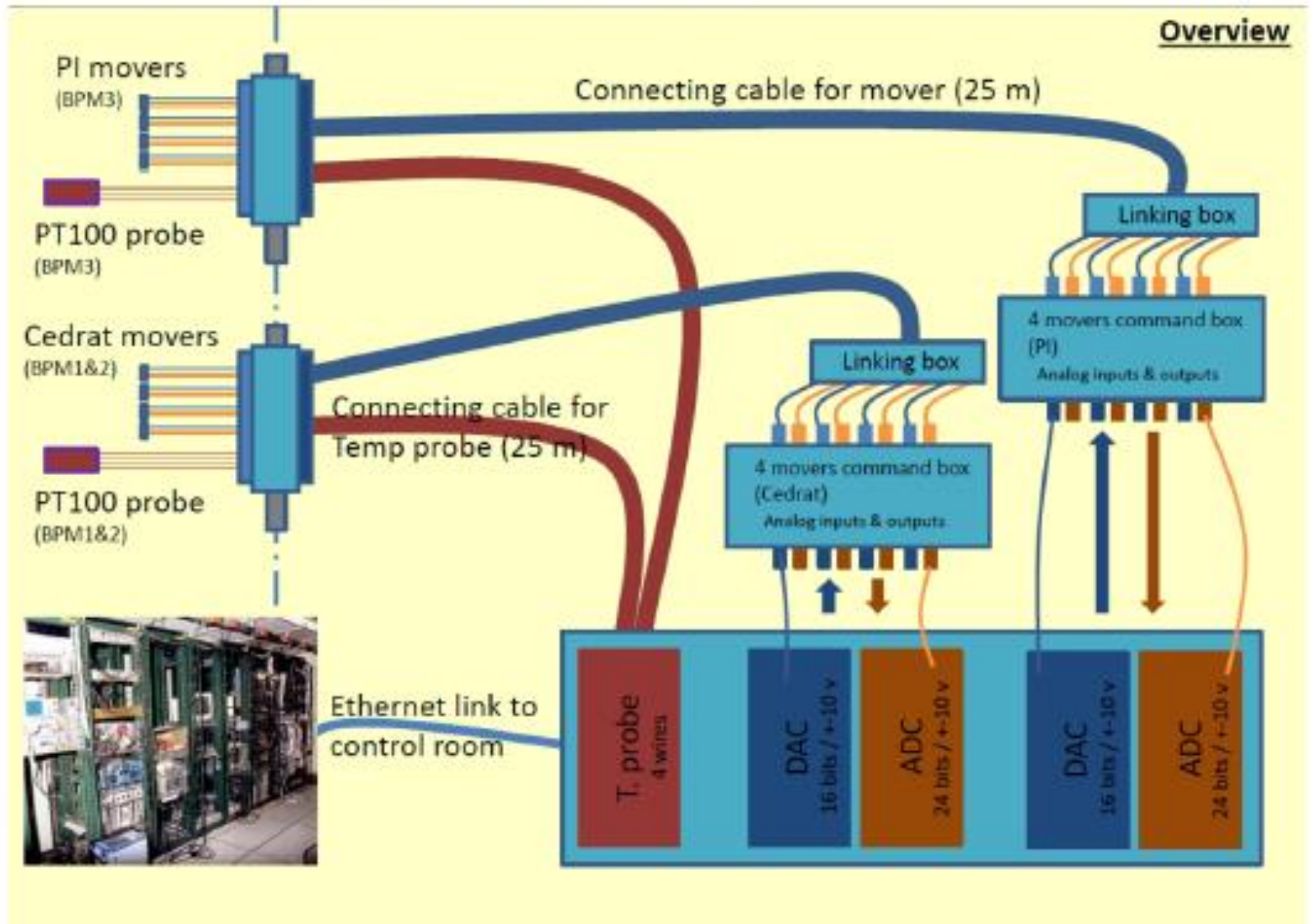
- ▶ Locate BPMs to enable the **maximum possible** beam position resolution
- ▶ Precision $\sim 5\mu\text{m}$
- ▶ Calibration $\sim 10^{-4}$



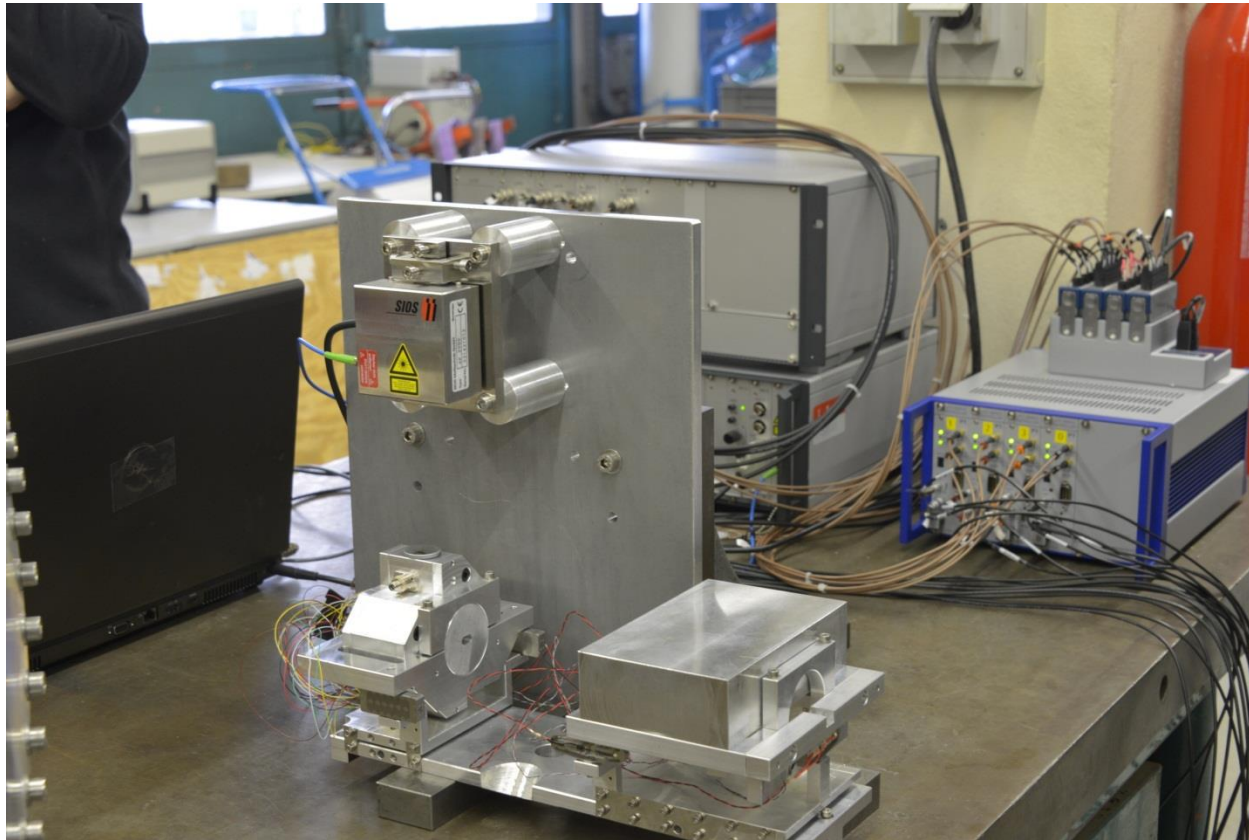
Displace each BPM block **independently**



How to control the piezo movers?



Piezo-mover performance checks performed at LAL before installation used Sios interferometer, with a weight representing IP-BPM block 1&2 and identical cabling

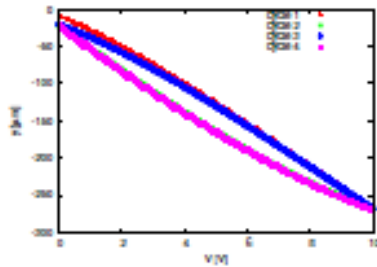


- Closed-loop stability
- Open-loop stability
- Setting accuracy
- Calibration
- Thermal effects
- Vibration mitigation

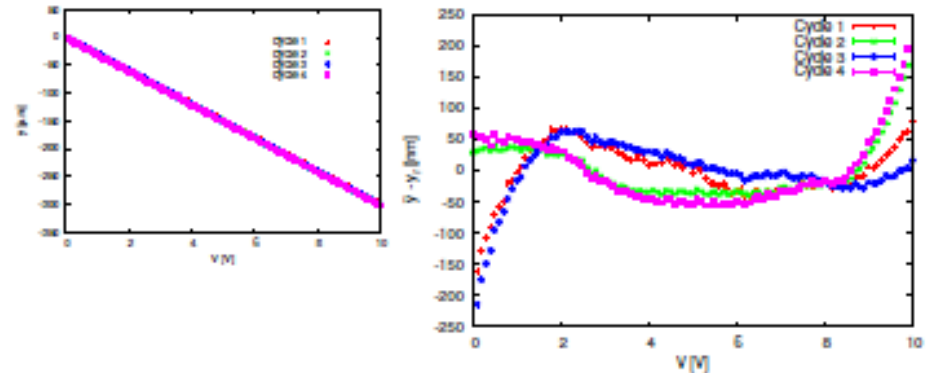
Linearity over 300 / 250 μm range $\rightarrow 10^{-3} - 10^{-4}$ (much better by parameterizing calibration curve)

Four cycles, range (0~10V, 0~300 μm)

PI without fb

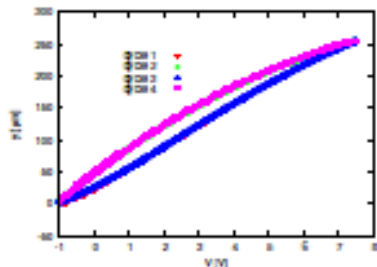


PI with fb

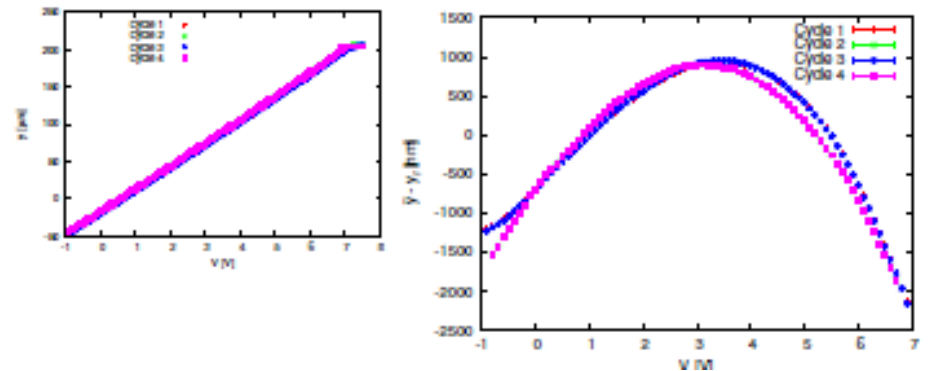


Four cycles, range (-1~7V, 0~250 μm)

Cedrat without fb



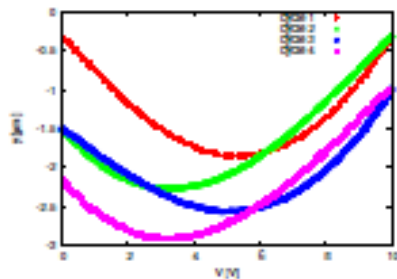
Cedrat with fb



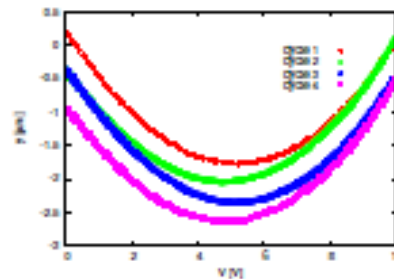
Coupling of horizontal motion into vertical over 300 / 250 μm range $\rightarrow 10^{-2}$

Four cycles, range (0~10V, 0~300 μm)

PI without fb



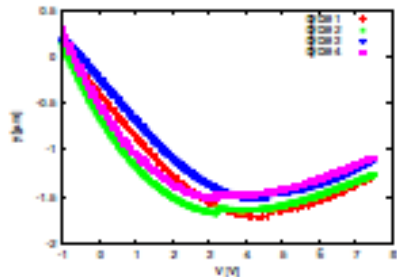
PI with fb



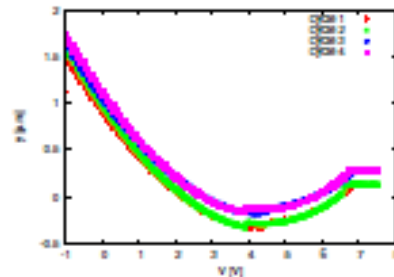
Coupling of 3 μm over all lateral range, equivalent to (1%)

Four cycles, range (-1~7.0V, 0~250 μm)

Cedrat without fb



Cedrat with fb

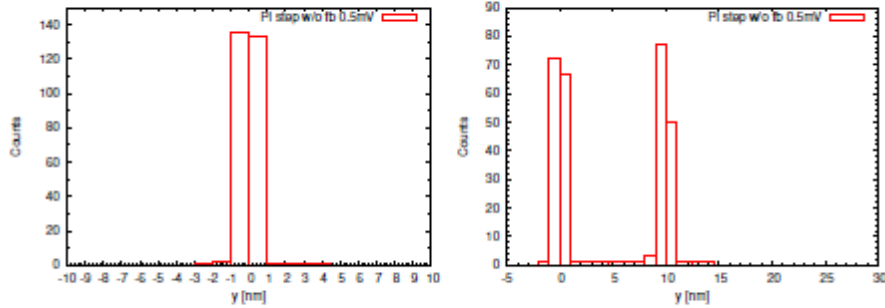


Coupling of 2.5 μm over all lateral range, equivalent to (1%)

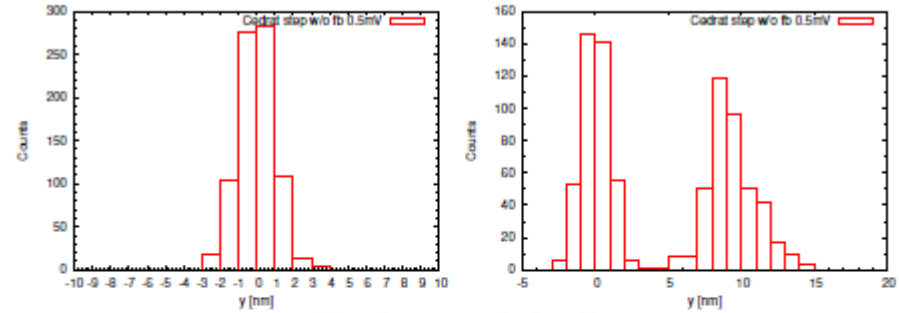
Stability ~ 1 nm in with feedback

Resolution < 10 nm

PI without fb

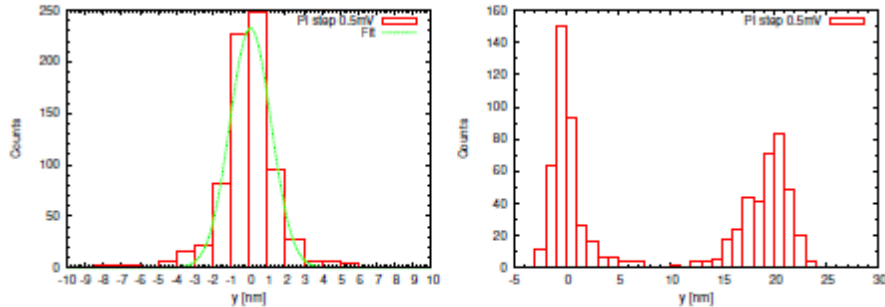


Cedrat without fb



PI with fb

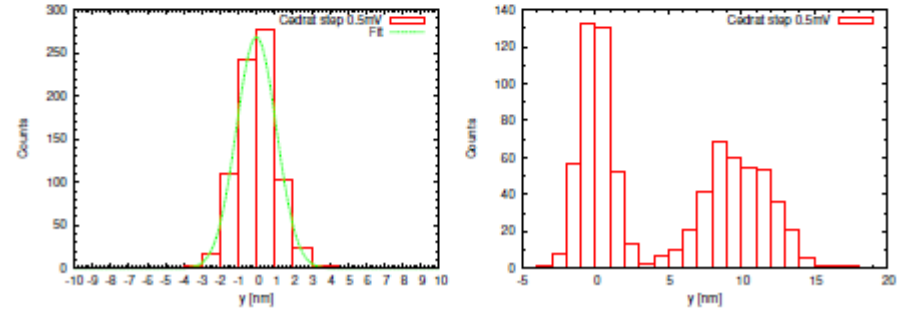
$\sigma = 1.13$ nm



0.5mV \rightarrow 15nm

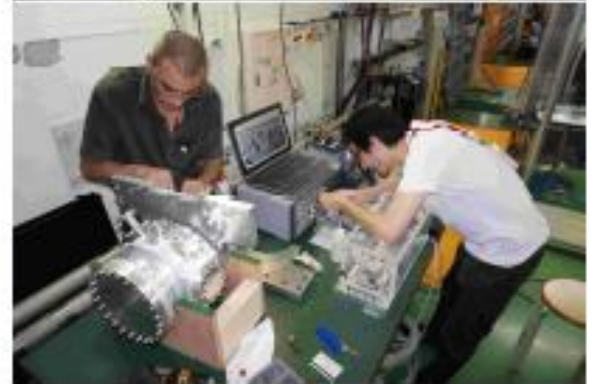
Cedrat with fb

$\sigma = 1.1$ nm



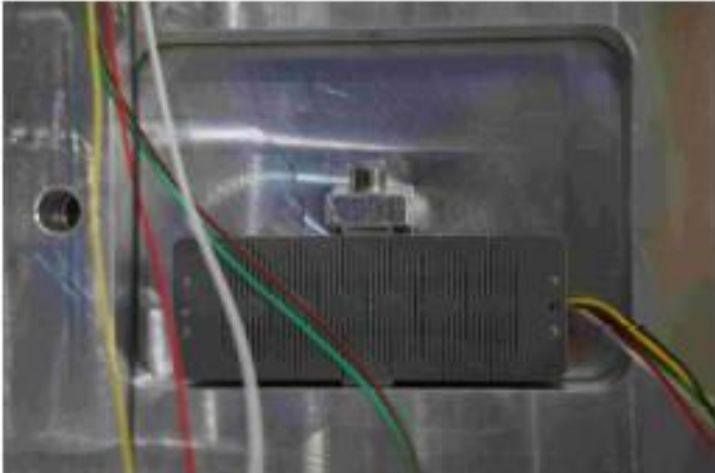
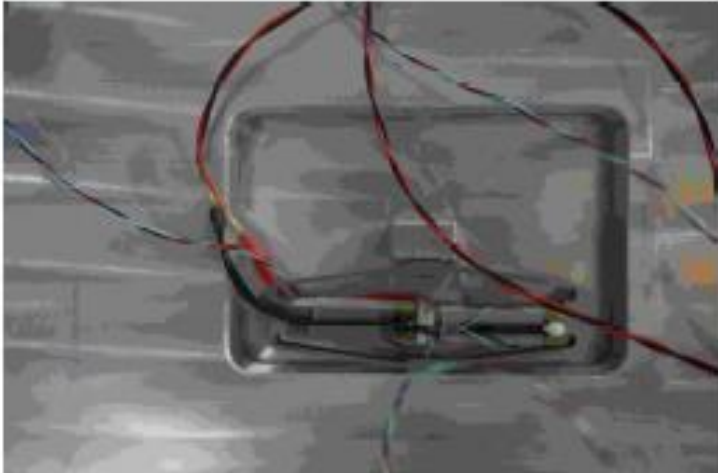
0.5mV \rightarrow 15.625nm

Unpacking and setting up



Mechanical Alignment

Lateral



Vertical



Rotation



Chamber installation and system first insertion



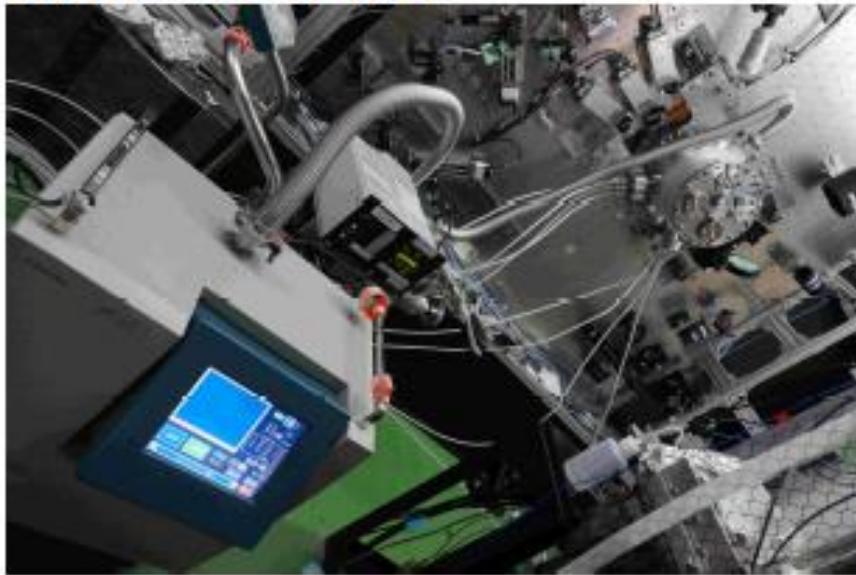
Cable modifications



Flanges installation



and vacuum test

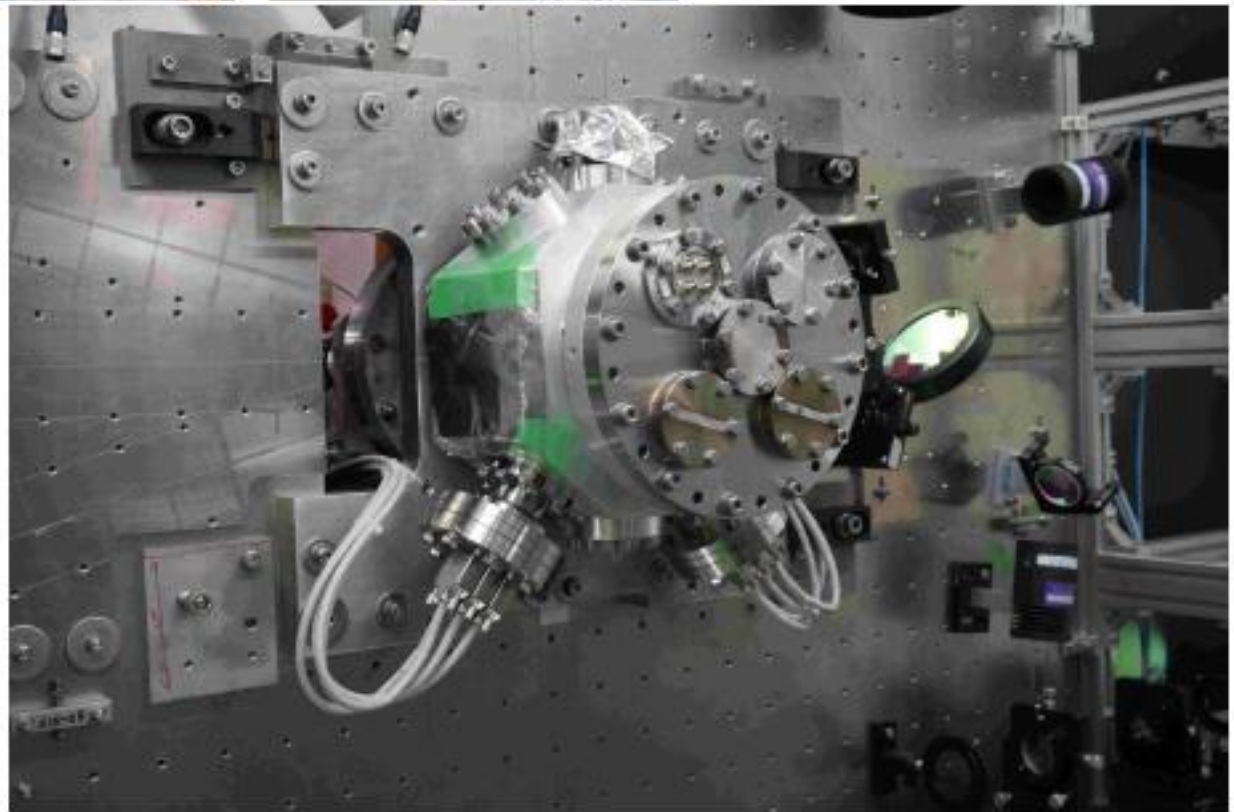


Pressure $2.8 \times 10^{-3} \text{ Pa} \rightarrow 10^{-4} \text{ Pa}$

Damping ring pressure 10^{-6} Pa

Positioning test was performed with readback from strain gauges

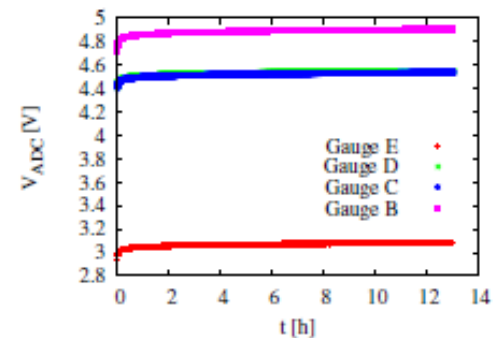
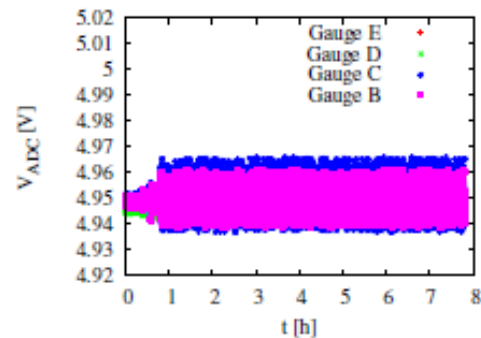
Cabling outside IP



Issue after installation: suddenly increased noise in strain gauge read-back on all PI piezo-movers

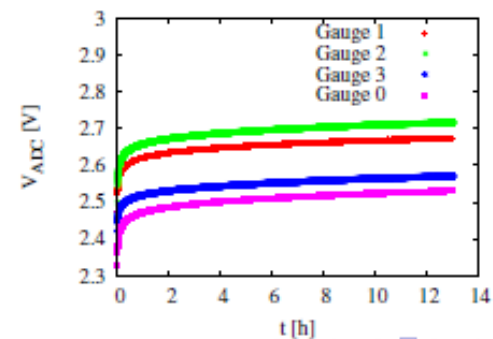
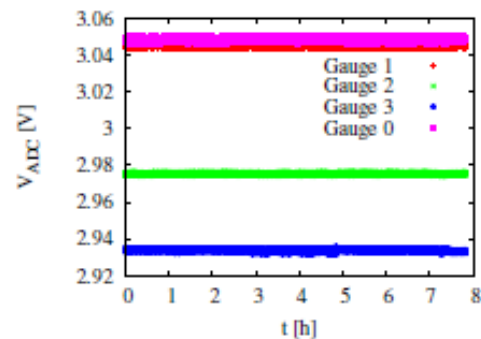
Stability (PI 1mV~30nm, Cedrat 1mV~31.25nm)

PI at 5V (fb, $\sigma \leq 1.4\text{mV} \rightarrow 5.3\text{mV}$) (no fb, $\sigma \leq 1.6\text{mV}$)



Cedrat at 3V (fb, $\sigma \leq 0.8\text{mV}$)

(no fb, $\sigma \leq 0.6\text{mV}$)



Before installation: 1-2 mV on all PI and Cedrat channels

PI Strain Gauges – After Installation

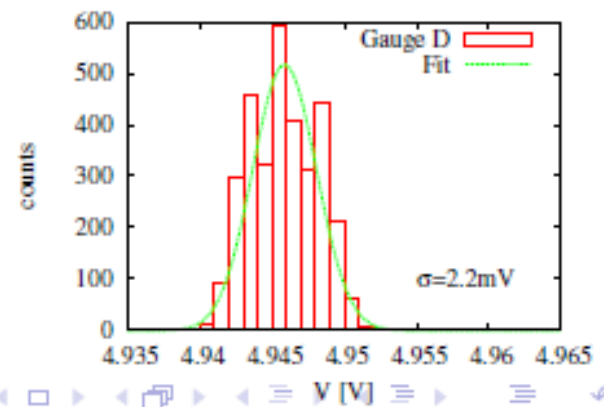
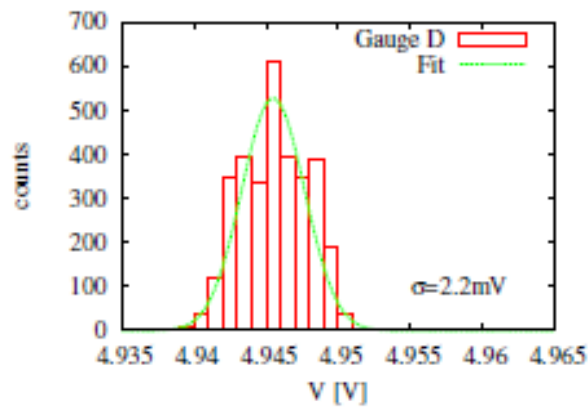
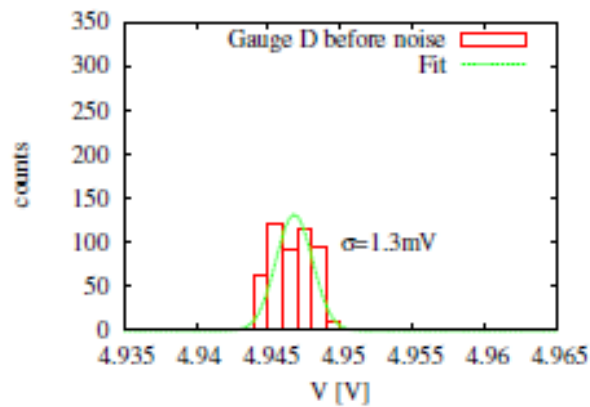
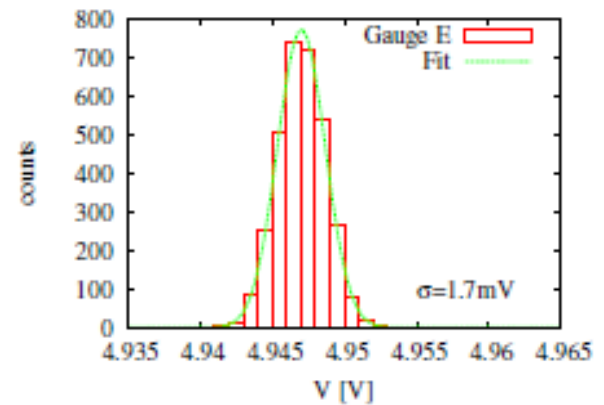
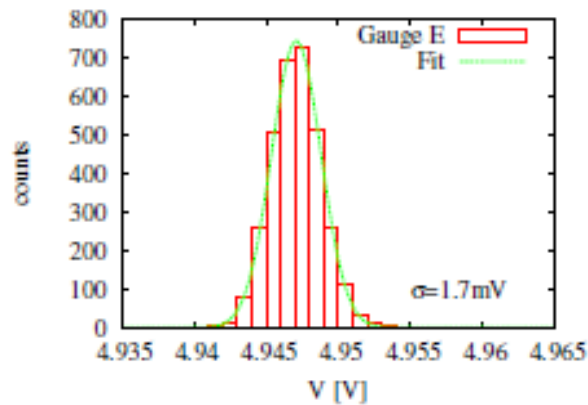
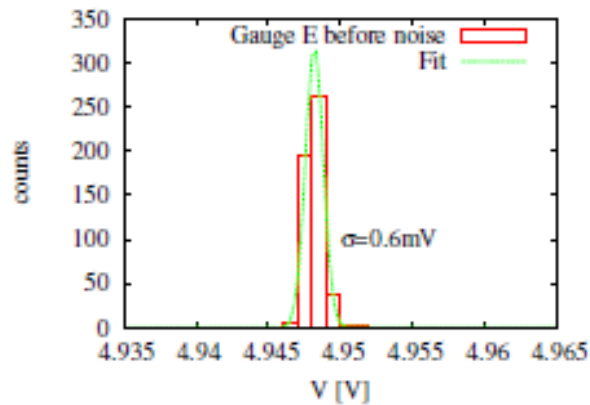
VERTICAL MOVERS

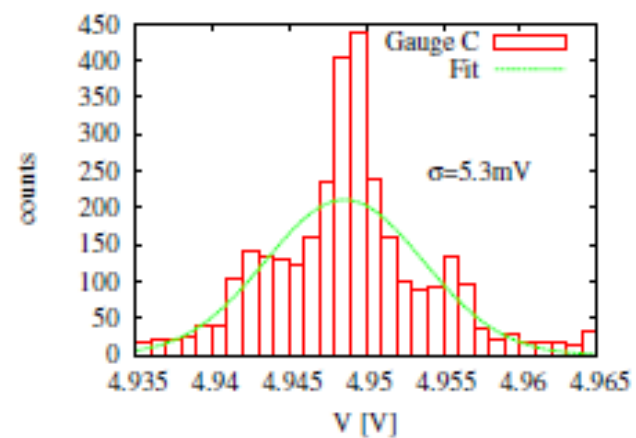
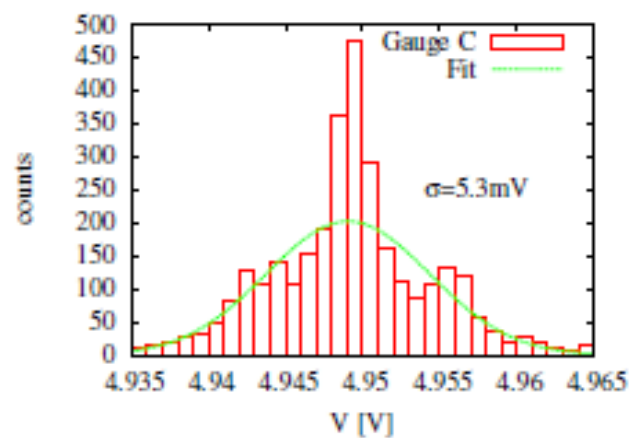
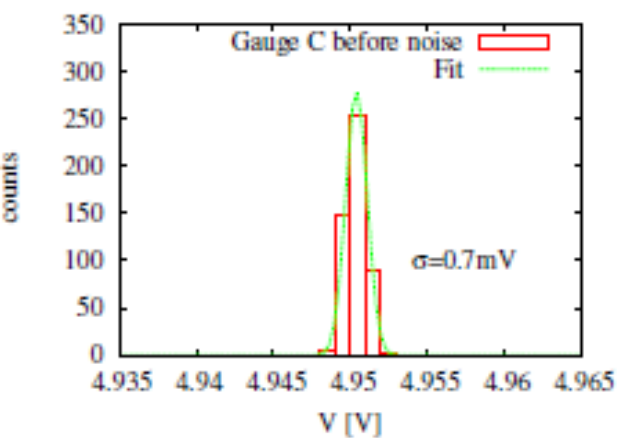
Remotely

Before noise

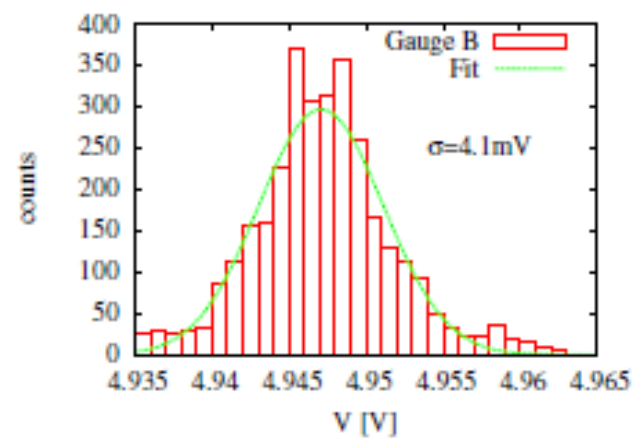
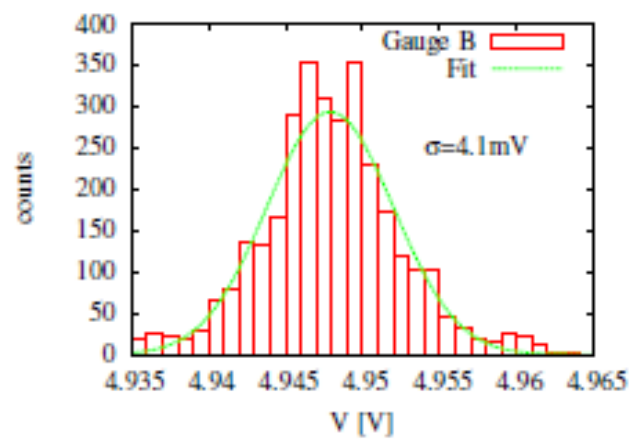
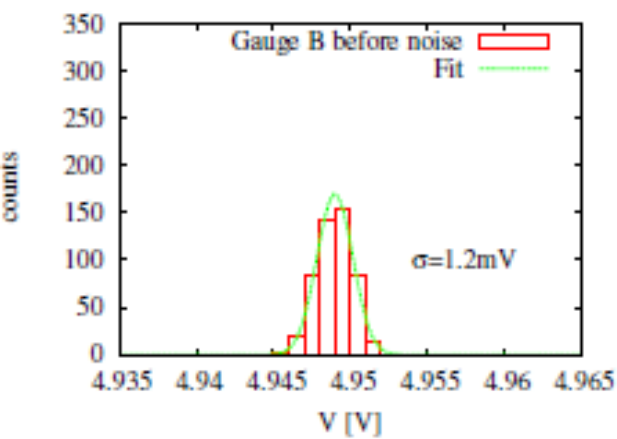
First test

Second test (swap)





LATERAL MOVER

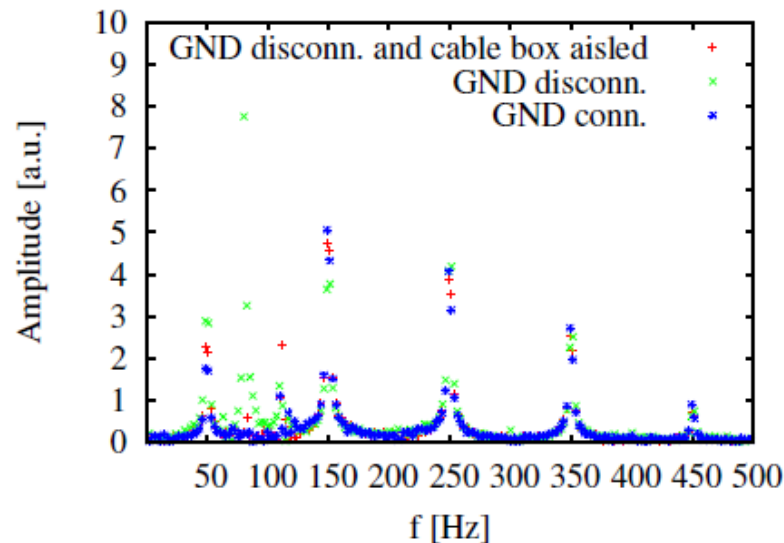


Will revisit the connection of grounds (and do a number of other checks)

GND connection

Just one channel was analyzed (PI E)

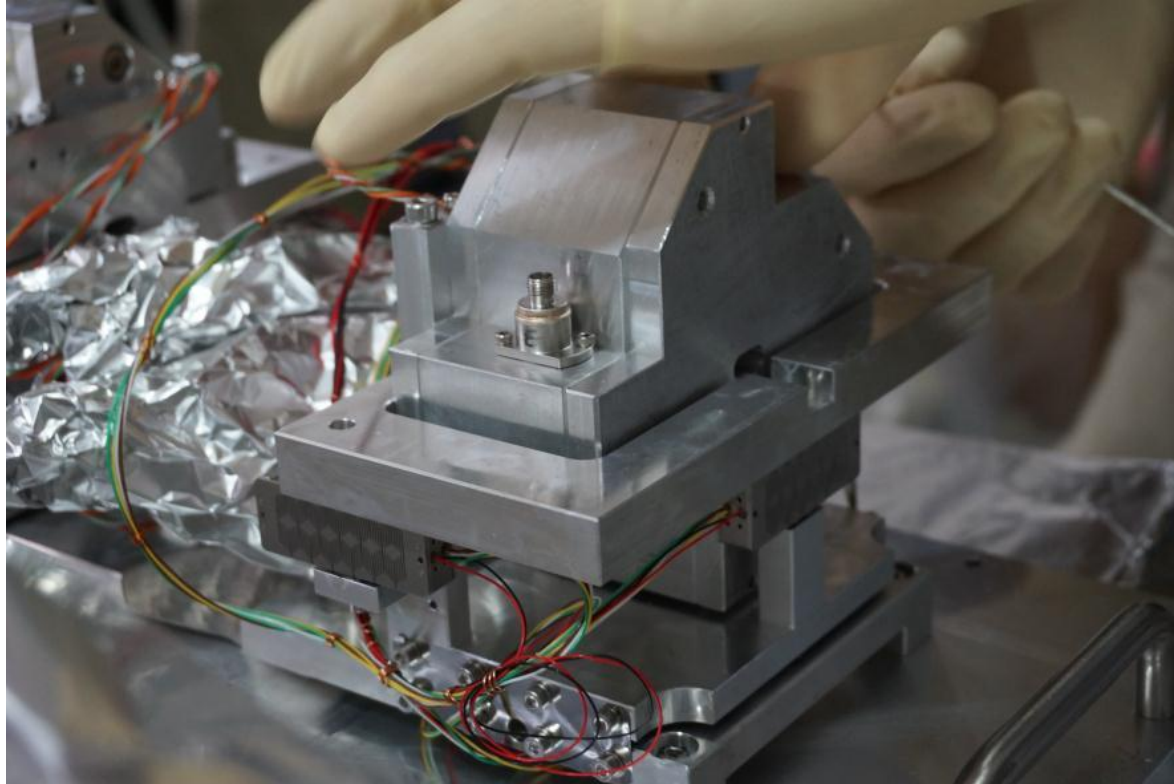
When GND is **disconnected**, additional frequency components were present.



We chose **GND connected**.

Increased noise in strain gauge read-back does not necessarily affect actual position stability

Pre-design for in situ measurements stability and calibration of strain gauge readout



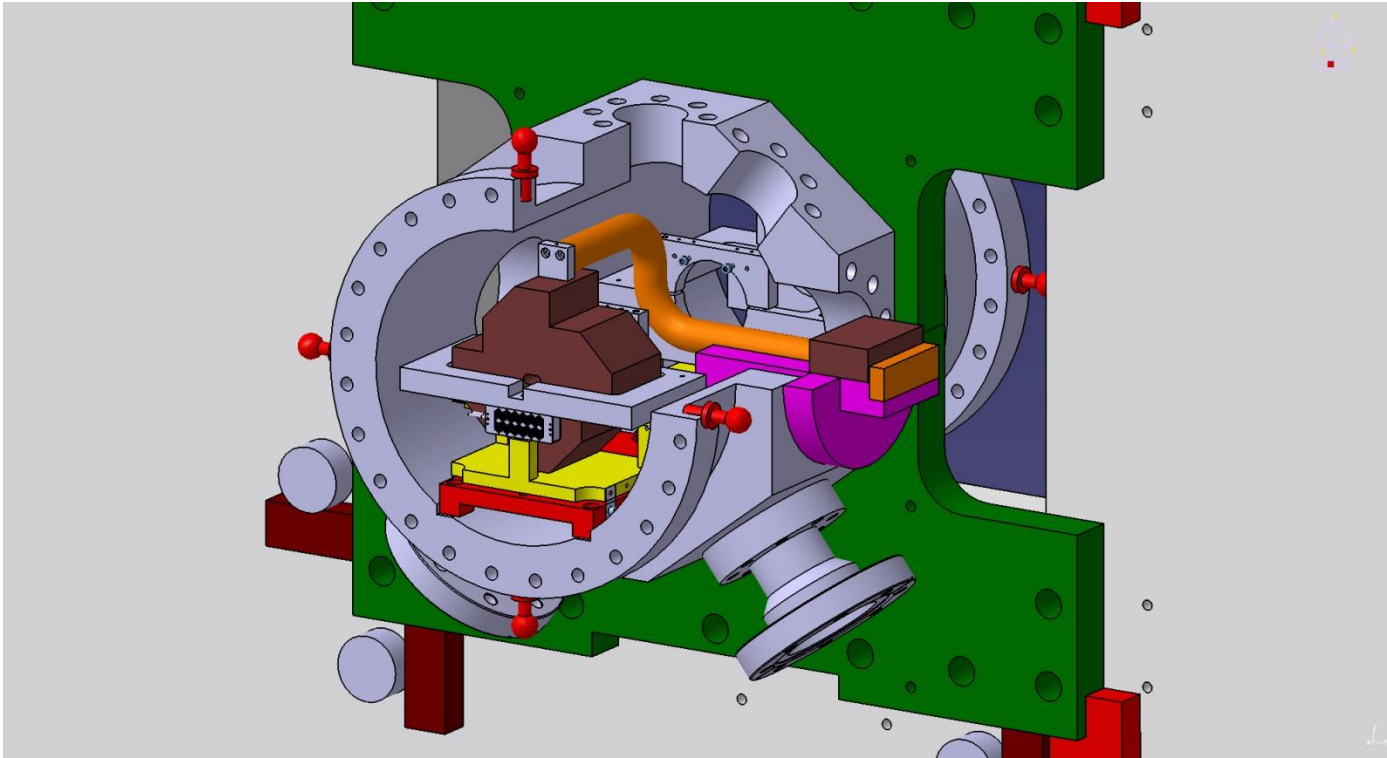
BPMs are moved with a set of piezo actuators

Feedback given by strain gauges

→ expected resolution : typically 20-30 μm

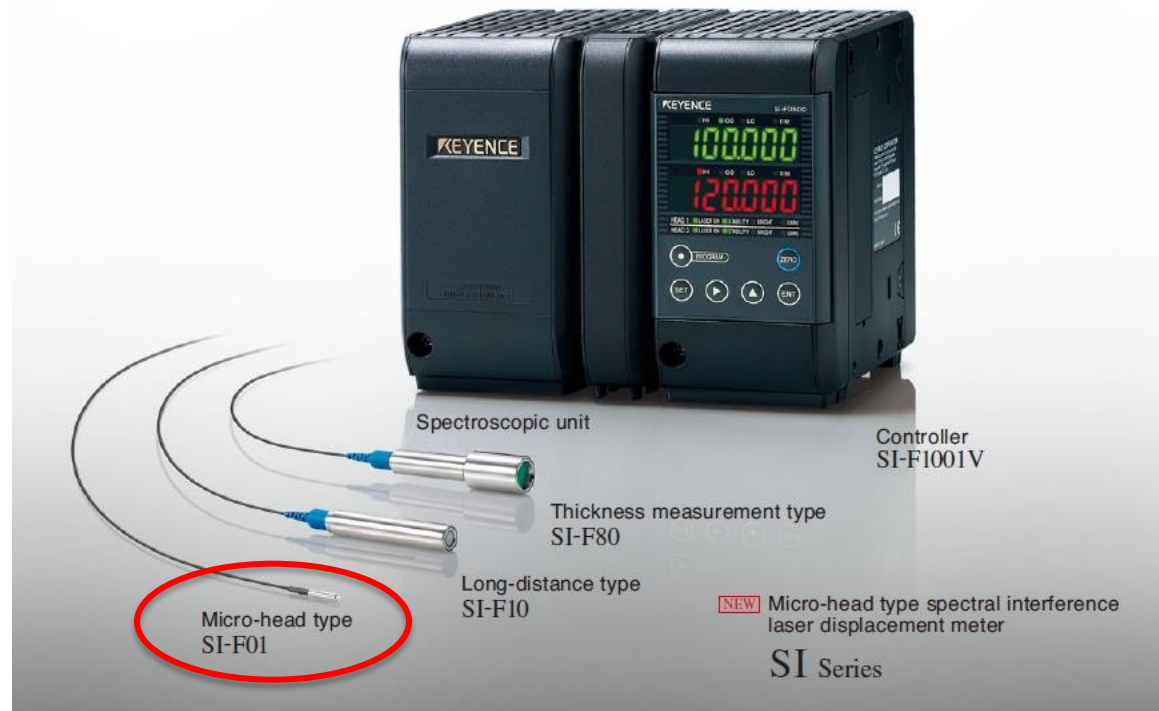
→ Strain gauges do not provide a feedback of actual BPMs displacement, but dilatation of a part of piezo elts stacking

A 1st way to measure the true BPMs vertical displacement



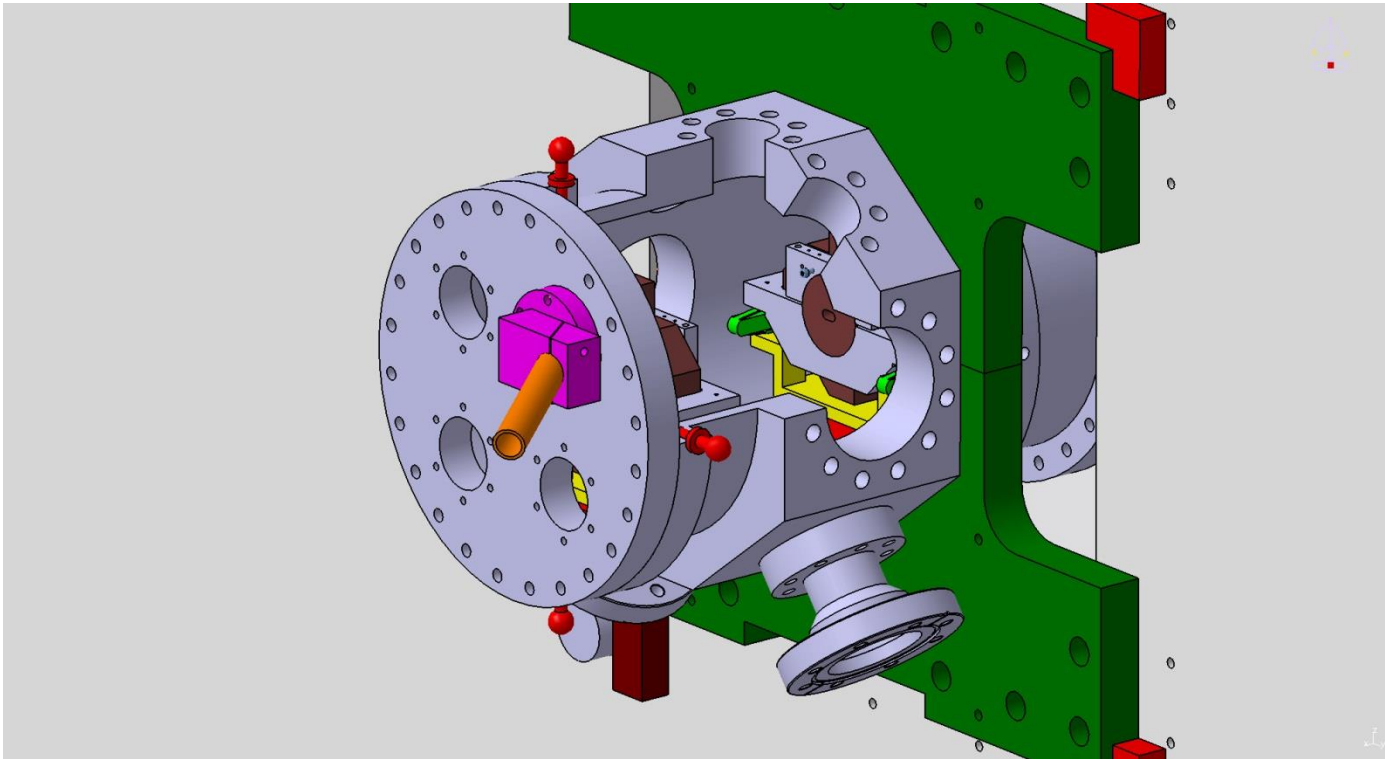
- Access : lateral viewport
- Stiff bent arm (no joint)
- Miniature interferometer probe w/ fiber optic (Keyence)

A 1st way to measure true BPMs vertical displacement



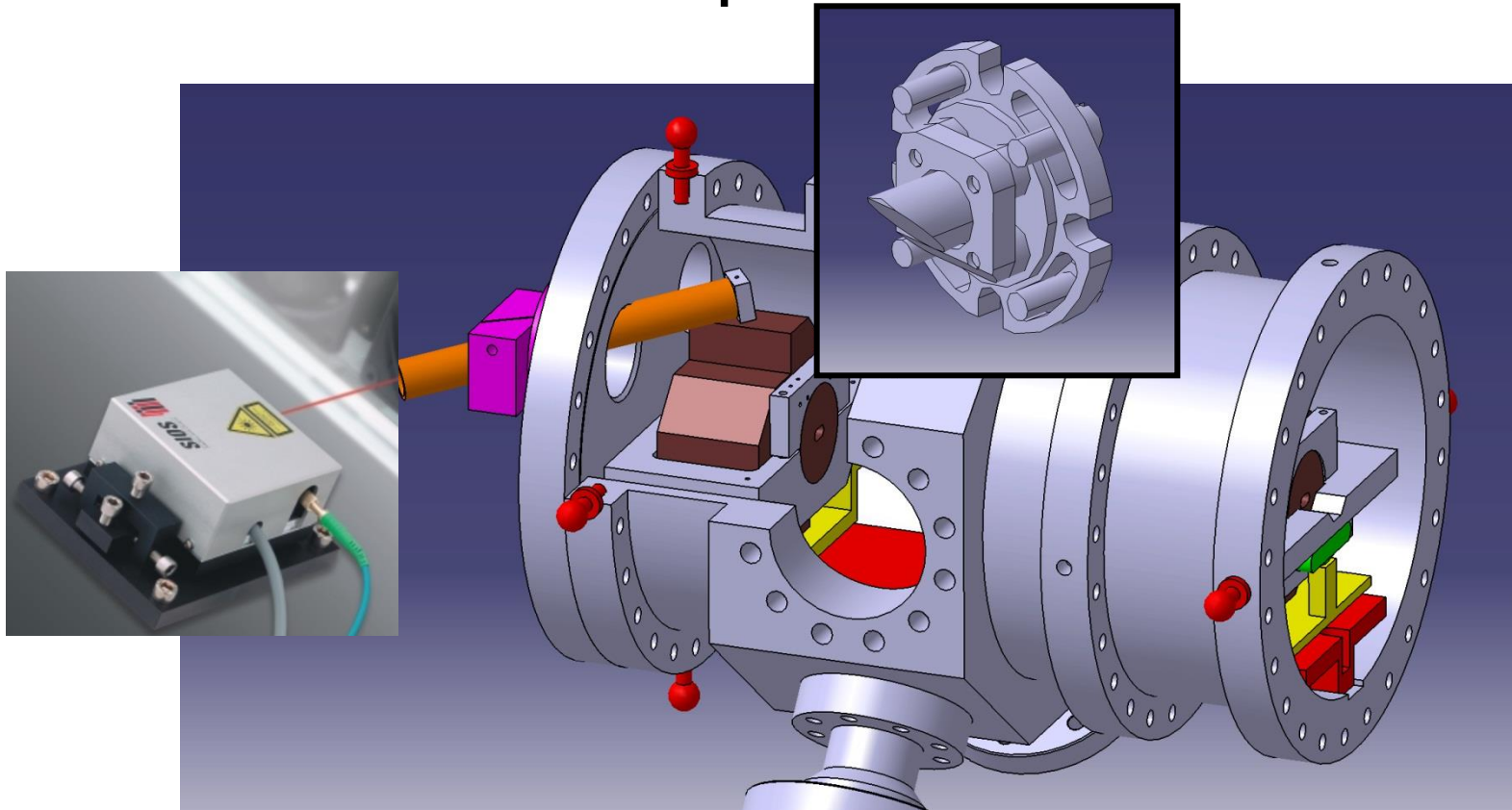
- 2 mm diameter miniature interferometer probe
- 1 nm resolution / 0.2 μm linearity

A 2nd way to measure the true BPMs vertical displacement



- Access : big end flange
- Miniature interferometer probe (Keyence)
- Or existing interferometer (SIOS) with 45 deg mirror

A 2nd way to measure the true BPMs vertical displacement



- Access : big end flange
- Miniature interferometer probe (Keyence)
- Or existing interferometer (SIOS) with 45 deg mirror

Pros and cons

Design	Access	Interferometer	Pros	Cons
1	Viewport 2-8-30 deg	Keyence	No mirror to place inside chamber Seems user friendly Very small and light (< 1 kg) 1 nm resolution	Viewport to remove 0.05 to 1.1 mm range Cost : 20000 €
2	End flange(s)	Same	Same	How to reach BPM1&2 : long arm (carbon fiber)? Mounting at upstream flange (awkward)?
3	End flange(s)	SIOS	0.1 nm resolution Already used, tested and bought Lab device with Press. & Temp. correction and invar head → high stability for long time measurements	Same as 2 plus : Mirror to place on BPM Cannot aim BPM central top surface Large electronic / power supply unit (150 x 450 x 40 cm ; 9.5 kg) to export

Conclusions and prospects

- A precise mover system, needed for goal 2, has been installed at the IP of ATF2
 - precise remote mechanical alignment of IP-BPMs
 - mechanical calibrations of IP-BPM scale factors with required precision, complementing determinations based on measuring beam fluctuations
- Experienced and studies using the setup in next runs
- Preparing in situ interferometer based monitoring for stability and strain gauge calibration
 - Tests to perform with existing interferometer (using 45 deg. mirror)
 - Purchase of new interferometer under consideration (if budget allows)
 - Plan for possible installation / implementation in summer 2014

Stay tuned for goal-2 results with the IP-BPMs !